

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:	) Confirmation No.: 1187
Koichiro TANAKA et al.	) Examiner: Sang Yeop Paik
Serial No. 10/579,238	) Group Art Unit: 3742
Filed: May 12, 2006	)
For: LASER IRRADIATION APPARATUS	)
AND LASER IRRADIATION METHOD	)

**RESPONSE**

Honorable Commissioner of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

The Official Action mailed November 1, 2011, has been received and its contents carefully noted. This response is filed within three months of the mailing date of the Official Action and therefore is believed to be timely without extension of time. Filed concurrently herewith is a *Request for Continued Examination*. Accordingly, the Applicant respectfully submits that this response is being timely filed.

The Applicant notes with appreciation the consideration of the Information Disclosure Statements filed on May 12, 2006; July 1, 2009; February 2, 2010 and August 17, 2011.

A further Information Disclosure Statement is submitted herewith and consideration of this Information Disclosure Statement is respectfully requested.

Claims 1-9, 11-20 and 22 are pending in the present application, of which claims 1-3, 9 and 11 are independent. For the reasons set forth in detail below, all claims are believed to be in condition for allowance. Favorable reconsideration is requested.

Paragraph 2 of the Official Action rejects claims 1-5, 7-9 and 11-16 as obvious based on the combination of U.S. Patent No. 6,246,524 to Tanaka '524, U.S. Patent No. 6,291,320 to Yamazaki '320, U.S. Patent No. 6,393,042 to Tanaka '042, JP 2003-